# Monthly LabAdviser update: 26/9 2012

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| Updated Subject  | Contributer | Link to the update pages |
| Deposition of Silicon oxideIn PVD co-sputter | Katharina Nilson@danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Silicon_Oxide><http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Silicon_oxide_in_PVD_co-sputter/evaporation> |
| Deposition of polySi using LPCVD | Pernille Voss Larsen@ DanchipMikkel M. Dysseholm @ Danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_polysilicon/Deposition_of_polysilicon_using_LPCVD><http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/B4_Furnace_LPCVD_PolySilicon> |
| AOE:Etching of micro structures in Silicon Oxide with PolySi as masking material | Berit Herstrøm@Danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Etching_of_Silicon_Oxide/SiO2_etch_using_AOE><http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Etching_of_Silicon_Oxide/SiO2_etch_using_AOE/Images_of_AOEpsiB_2> |
| PECVD: Expected results of silicon oxide and silicon nitride deposition | Berit Herstrøm @Danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Silicon_Oxide/Deposition_of_Silicon_Oxide_using_PECVD><http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Silicon_Nitride/Deposition_of_Silicon_Nitride_using_PECVD> |
| DRIE-PegasusDevelopment of switched nanoetch process | Jonas Michael-Lindhard@Danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/DRIE-Pegasus/nanoetch> |
| Thermal processPhosphor pre-dep and Bor pre-dep | Mikkel M. Dysseholm @ Danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thermal_Process/A2_Furnace_Boron_pre-dep><http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thermal_Process/A4_Furnace_Phosphorus_pre-dep> |
| III-V photolithography | Jesper Hanberg @Danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/III-V_Process/photolithography/III_V_Photolithography> |
| Multisource PVD | Katharina Nilson@Danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Multisource_PVD> |